

Amendments to the Claims:

This listing of claims will replace all prior versions, and listings of claims in the application:

Listing of Claims:

1. (canceled)
2. (canceled)
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33. (canceled)

34. (currently amended) A method of resetting a threshold using a display coupled with a computer, said method comprising:

displaying a first standard on said display, said first standard used to select defect candidate ~~image indications to store~~ images among defect candidate images stored in a memory beforehand ~~and to be shown on a defect candidate distribution screen of said display;~~

graphically displaying on said display a distribution of defects in a wafer map format in which said defects are selected from said defect candidate images stored in said memory by applying said first standard ~~a relation between defect density and threshold in which said first standard is indicated;~~

changing said first standard to a second standard on said display; and

changing said graphical display of wafer format in response to said change to said second standard by applying said second standard to said defect candidate images ~~image indications selected by said first standard and~~ stored in said memory.

35. (original) The method of claim 34 further comprising:

selecting a selected indication of said defect candidate image indications; and
viewing an inspection image associated with said selected indication.

36. (previously presented) The method of claim 34 wherein said first standard is calculated using an electron beam noise value for a SEM system.

37. (canceled)

38. (canceled)

39. (currently amended) A method in a computer system for displaying a defect candidate, said defect candidate stored in a memory with an expanded view of said defect candidate, said method comprising:

displaying a two-dimensional defect candidate distribution ~~for a standard in a wafer map format~~ on a first screen in which defect candidates displayed on said first screen are selected from said defect candidate images stored in a memory by applying a standard;
~~said two-dimensional defect candidate distribution comprising an indication of said defect candidate; and~~

displaying on a second screen ~~said an~~ expanded view of said defect candidate stored in said memory, responsive to a selection of ~~said indication~~ a defect candidate among defects in said wafer map format displayed on said first screen,

wherein said two-dimensional defect candidate distribution displayed on said first screen changes by changing said standard.

40. (original) The method of claim 39 wherein said expanded view comprises an image associated with said defect candidate and selected from a group consisting of a clipped inspection image, a clipped reference image, or a defect candidate image.

41. (original) The method of claim 39 wherein said expanded view comprises a re-scanned image of said defect candidate.

42. (original) The method of claim 39 further comprising a threshold screen for changing said threshold.

43. (original) The method of claim 39 further comprising a screen displaying a graph of defect density versus threshold.

44. (original) The method of claim 39 wherein said two-dimensional defect candidate distribution displays defect candidates responsive to a user selected area.

45. (original) The method of claim 39 wherein said two-dimensional defect candidate distribution displays defect candidates by type of defect.

46. (original) The method of claim 45 wherein each type of defect has a different symbol, said defect being displayed using a symbol.

47. (withdrawn) The method of claim 45 wherein each type of defect has an associated threshold value.

48. (original) The method of claim 39 wherein said two-dimensional defect candidate distribution displays defect candidates as symbols.

49. (original) The method of claim 48 wherein a symbol of said symbols comprise a grayscale value.

50. (withdrawn) The method of claim 49 wherein said grayscale value is related to a margin.

51. (original) The method of claim 49 wherein said grayscale value is related to an enhanced result.

52. (original) The method of claim 48 wherein a symbol of said symbols comprise a color value.

53. (original) The method of claim 48 wherein a symbol of said symbols comprise a black or a white value.

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83. (previously presented) The method of claim 34 wherein the graphical display which is changed in response to said change to said second standard is used to judge an effect of said change to said second standard.

84. (previously presented) The method of claim 83 wherein the graphical display which is changed in response to said change to said second standard is used to judge whether said change to said second standard is proper.

85. (previously presented) The method of claim 39 further comprising changing said standard to change said two-dimensional defect candidate distribution displayed on said first screen.

86. (previously presented) The method of claim 85 wherein said two-dimensional defect candidate distribution displayed on said first screen which is changed in response to said change of said standard is used to judge an effect of said change of said standard.

87. (previously presented) The method of claim 86 wherein said two-dimensional defect candidate distribution displayed on said first screen which is changed in response to said change of said standard is used to judge whether said change of said standard is proper.

88. (new) The method of claim 34 further comprising graphically displaying a relation between defect density and threshold in which said first standard is indicated.

89. (new) A method of resetting a threshold using a display coupled with a computer and displaying a defect candidate, said defect candidate stored in a memory with an expanded view of said defect candidate, said method comprising:

displaying a first standard on said display, said first standard used to select defect candidate image indications to store in a memory and to be shown on a defect candidate distribution screen of said display;

graphically displaying a relation between defect density and threshold in which said first standard is indicated;

displaying a two-dimensional defect candidate distribution for said first standard on a first screen, said two-dimensional defect candidate distribution comprising an indication of said defect candidate;

displaying on a second screen said expanded view of said defect candidate stored in said memory, responsive to a selection of said indication on said first screen;

changing said first standard to a second standard on said display; and

changing said graphical display of said relation in response to said change to said second standard by applying said second standard to said defect candidate image indications selected by said first standard and stored in said memory.

90. (new) The method of claim 89 wherein said two-dimensional defect candidate distribution displayed on said first screen changes by changing said first standard to said second standard.

91. (new) The method of claim 89 further comprising:
selecting a selected indication of said defect candidate image indications; and
viewing an inspection image associated with said selected indication.

92. (new) The method of claim 89 wherein said first standard is calculated using an electron beam noise value for a SEM system.

93. (new) The method of claim 89 wherein said expanded view comprises an image associated with said defect candidate and selected from a group consisting of a clipped inspection image, a clipped reference image, or a defect candidate image.

94. (new) The method of claim 89 wherein said expanded view comprises a re-scanned image of said defect candidate.

95. (new) The method of claim 89 further comprising a threshold screen for changing said threshold.

96. (new) The method of claim 89 further comprising a screen displaying a graph of defect density versus threshold.

97. (new) The method of claim 89 wherein said two-dimensional defect candidate distribution displays defect candidates responsive to a user selected area.

98. (new) The method of claim 89 wherein said two-dimensional defect candidate distribution displays defect candidates by type of defect.

99. (new) The method of claim 98 wherein each type of defect has a different symbol, said defect being displayed using a symbol.

100. (new) The method of claim 98 wherein each type of defect has an associated threshold value.

101. (new) The method of claim 89 wherein said two-dimensional defect candidate distribution displays defect candidates as symbols.

102. (new) The method of claim 101 wherein a symbol of said symbols comprise a grayscale value.

103. (new) The method of claim 102 wherein said grayscale value is related to a margin.

104. (new) The method of claim 102 wherein said grayscale value is related to an enhanced result.

105. (new) The method of claim 101 wherein a symbol of said symbols comprise a color value.

106. (new) The method of claim 101 wherein a symbol of said symbols comprise a black or a white value.